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(54) MAGNETORESISTIVE SENSOR AND
MAGNETORESISTIVE HEAD, AND
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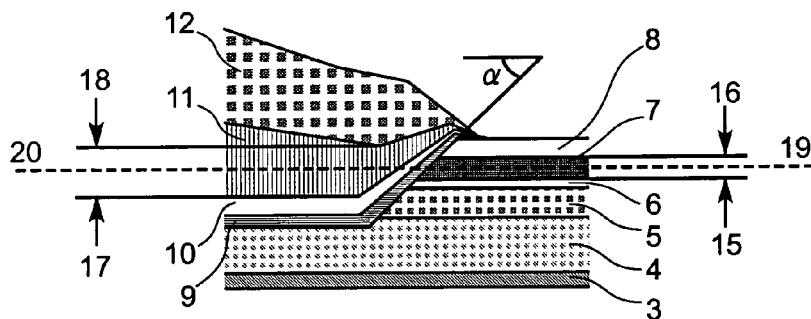
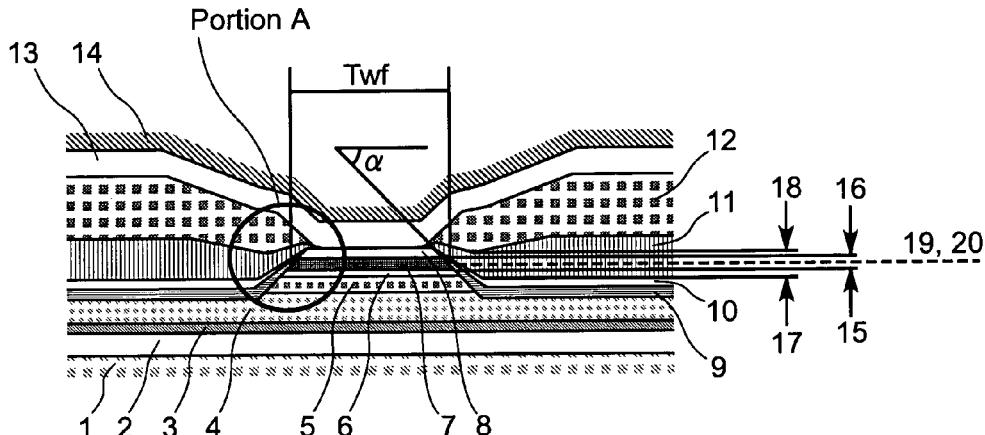
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(57) ABSTRACT

In a magnetoresistive head according to the present invention, a magnetic domain control film formed at the end of a free layer of a stack of magnetoresistive layers is formed of a Co alloy film, and an underlayer controlling the crystallization state of the Co alloy film and an amorphous metal film layer for controlling the crystallization state of the underlayer are disposed below the magnetic domain control film.



Enlarged view for portion A